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Choi et al.

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(54) **SUBSTRATE SUPPORTER FOR SEMICONDUCTOR DEPOSITION APPARATUS**
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(**) Term: **14 Years**

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(30) **Foreign Application Priority Data**

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(51) **LOC (10) Cl.** **13-03**

(52) **U.S. Cl.**
USPC **D13/182**

(58) **Field of Classification Search**
USPC D13/182; 118/500, 715, 728, 729;
156/345.51, 345.52, 345.53, 345.55;
279/128; 361/234; 414/217, 220.01,
414/416.03, 935, 936, 937, 939, 940, 941
See application file for complete search history.

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(57) **CLAIM**

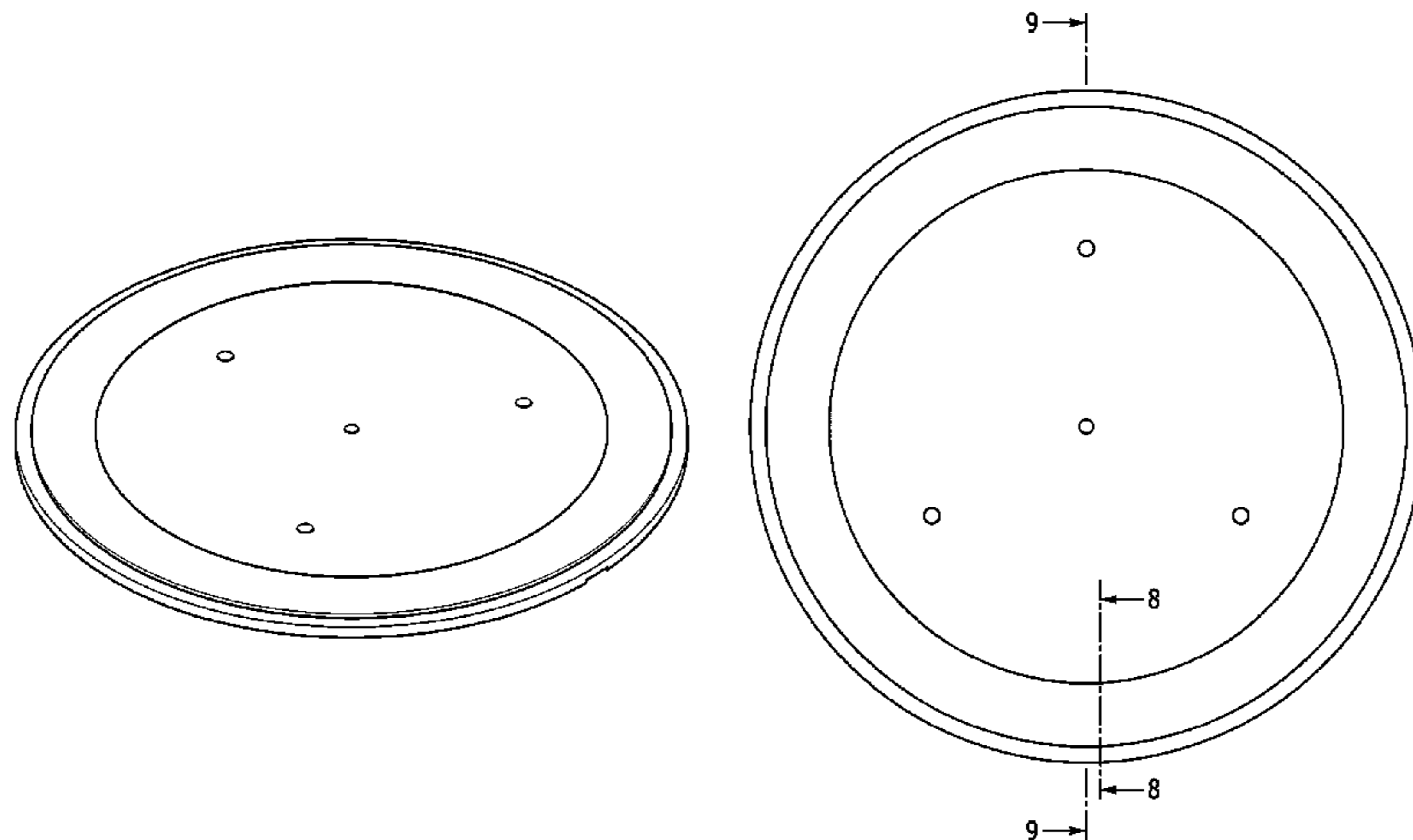
The ornamental design for a substrate supporter for semiconductor deposition apparatus, as shown and described.

DESCRIPTION

FIG. 1 is a perspective view of a substrate supporter for a semiconductor deposition apparatus showing our new design;
FIG. 2 is a front elevation view thereof;
FIG. 3 is a rear elevation view thereof;
FIG. 4 is a left side elevation view thereof;
FIG. 5 is a right side elevation view thereof;
FIG. 6 is a top plan view thereof;
FIG. 7 is a bottom plan view thereof;
FIG. 8 is a cross sectional view thereof taken along line 8-8 in FIG. 6; and,
FIG. 9 is a cross sectional view thereof taken along line 9-9 in FIG. 6.

The broken lines shown in the drawings represent portions of the substrate supporter for a semiconductor deposition apparatus that form no part of the claimed design.

1 Claim, 9 Drawing Sheets



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FIG. 1

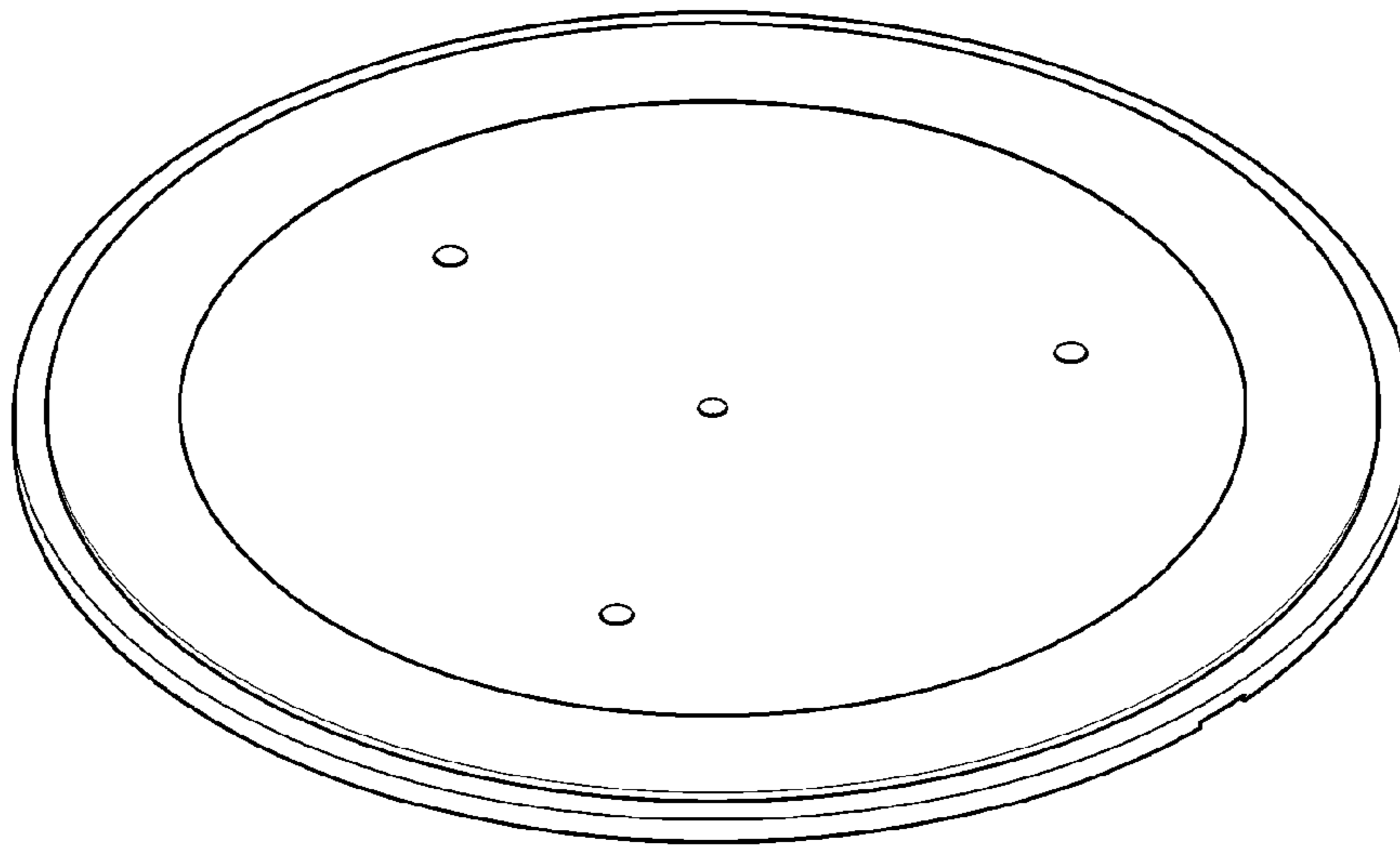


FIG. 2

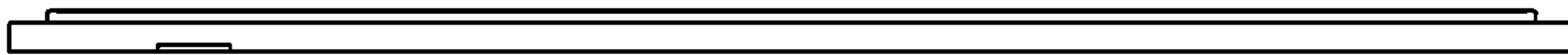


FIG. 3

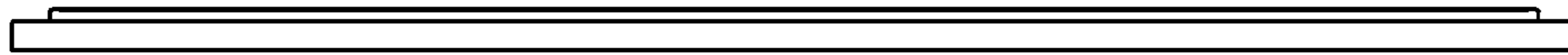


FIG. 4

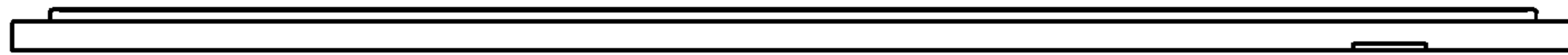


FIG. 5

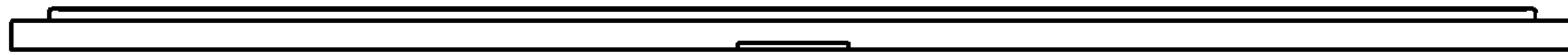


FIG. 6

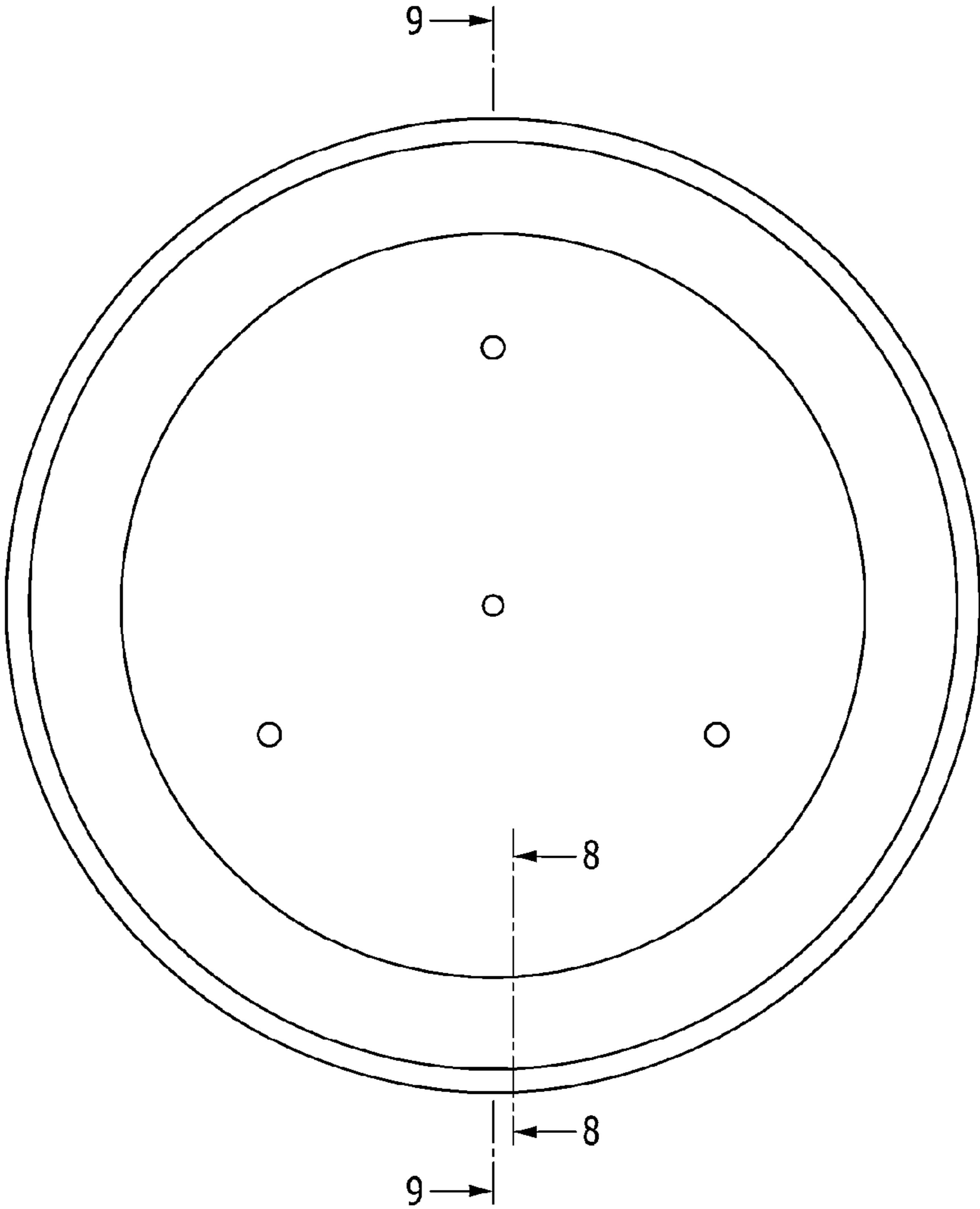


FIG. 7

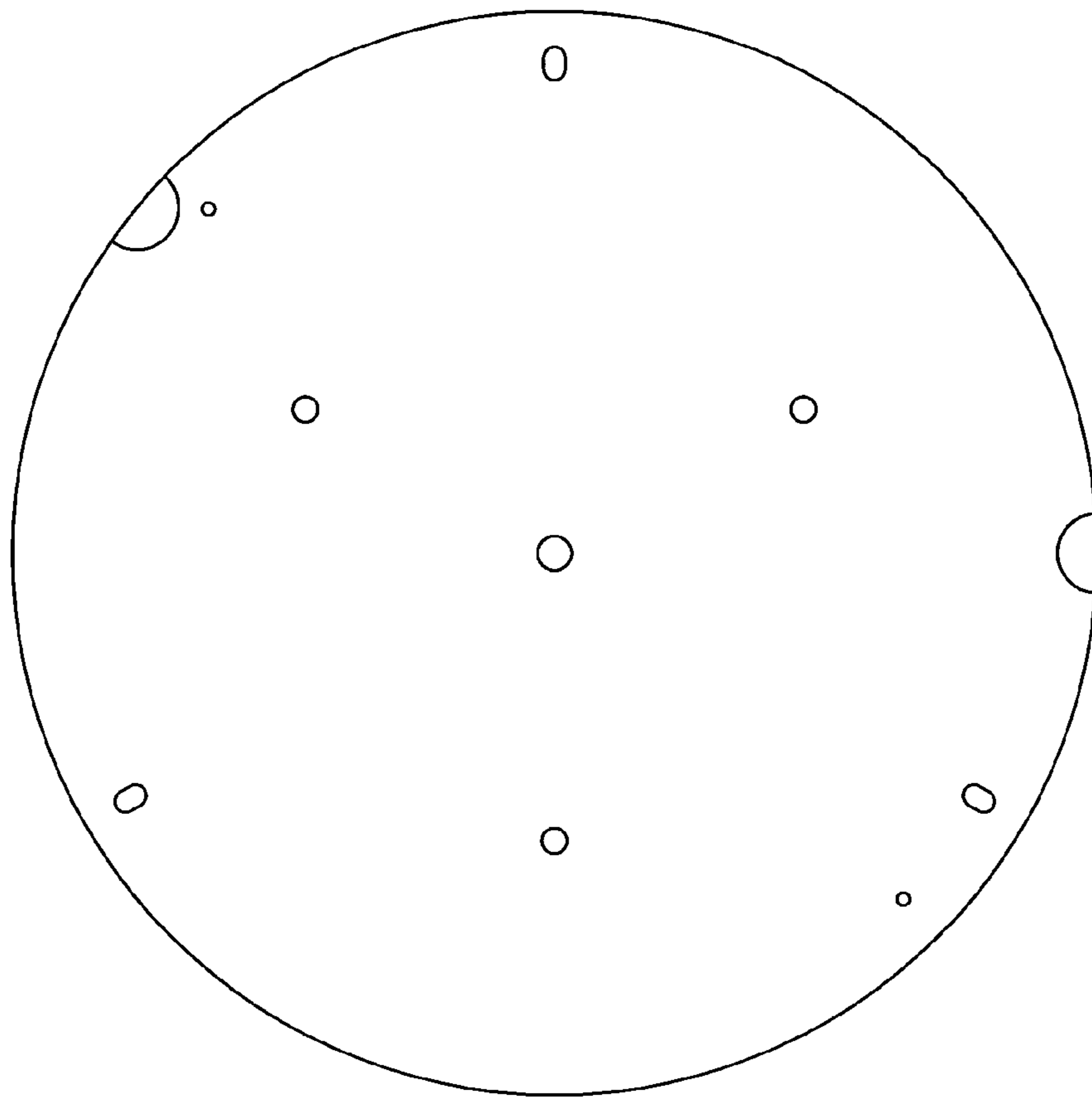


FIG. 8

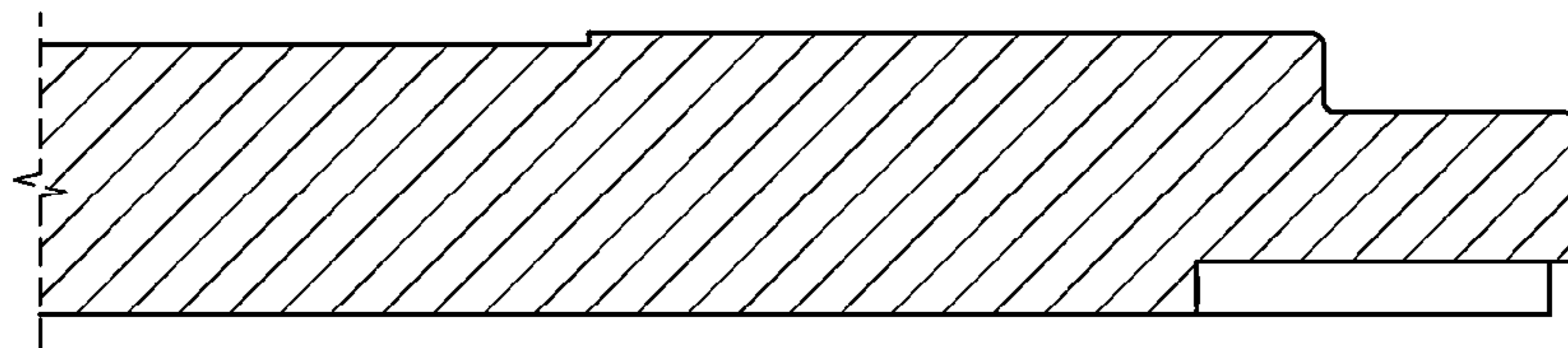


FIG. 9

